

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Van Beek, <i>et al.</i>	Docket No.:	EPC-019
Serial No.:	10/578,026	Conf. No.:	4725
Art Unit:	2829	Examiner:	Karen M. Kusumakar
Filed:	March 13, 2007		
For:	Method of Manufacturing a MEMS Device and MEMS Device		

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Dear Sir:

The following amendments and remarks are presented in response to the Examiner's Office Action mailed September 8, 2009. Please amend the above-referenced application as follows.